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### Supplementary Materials for

## Bioinspired mechano-photonic artificial synapse based on graphene/MoS<sub>2</sub> heterostructure

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#### This PDF file includes:

Supplementary Text Figs. S1 to S17 References

#### 1. Materials characterization of graphene, MoS<sub>2</sub>, and graphene/MoS<sub>2</sub> heterostructure

The Raman spectra of monolayer graphene grown by chemical vapor deposition (CVD) and  $MoS_2$  obtained by mechanical exfoliation are excited by 532 nm laser. **fig. S1A** shows the typical Raman spectra of graphene with G band at ~1593 cm<sup>-1</sup> and 2D band at ~2681 cm<sup>-1</sup>. The peak position of G and 2D band and the 2D/G peak intensity ratio at ~2.5 indicates the monolayer and high-quality characteristics of the graphene by CVD (*51, 52*). **fig. S1B** shows two typical Raman peaks of MoS<sub>2</sub> are located at ~382 and ~407 cm<sup>-1</sup>, corresponding to the in-plane  $E_{2g}$  mode and out-of-plane  $A_{1g}$  mode, respectively. The interval between the two peaks is 25 cm<sup>-1</sup>, indicating the multilayer character of MoS<sub>2</sub> (*53, 54*). The thickness of the fabricated graphene/MoS<sub>2</sub> (Gr/MoS<sub>2</sub>) heterostructure and patterned graphene is ~32 nm and ~1 nm, respectively, measured by atomic force microscopy (AFM) as shown in **fig.S1C**. The graphene thickness deviation from theoretical value of monolayer graphene (0.34 nm) may be due to the intrinsic non-precise measurement by AFM and imperfect substrate status.



**fig. S1. Materials characterization.** Raman spectrum of (**A**) monolayer graphene and (**B**) multilayer MoS<sub>2</sub>. (**C**) The AFM image of the Gr/MoS<sub>2</sub> heterostructure and graphene.

#### 2. Fabrication process of the mechano-photonic artificial synapse

The mechano-photonic artificial synapse based on Gr/MoS<sub>2</sub> heterostructure is fabricated following the process of MoS<sub>2</sub> transfer, Gr/MoS<sub>2</sub> heterostructure construction, graphene patterning, source and drain electrodes (Cr/Au) deposition and integration of triboelectric nanogenerator (TENG) component.



fig. S2. The fabrication process of the mechano-photonic artificial synapse based on  $Gr/MoS_2$  heterostructure.

#### 3. Optical image of each step for the Gr/MoS2 transistor fabrication

Few-layer MoS<sub>2</sub> is firstly mechanically exfoliated and transferred onto the SiO<sub>2</sub>/Si substrate by typical thermal transfer process. CVD graphene is transferred onto the MoS<sub>2</sub> flakes through polymethyl methacrylate (PMMA)-assisted wet transfer method. Then, the graphene is patterned by standard electron-beam lithography (EBL) process followed with e-beam deposition of ~15 nm Al metal layer (etching protective mask). After oxygen plasma etching, graphene is patterned into the strip shape  $(3 \times 20 \ \mu m^2)$ . Thus, the desired Gr/MoS<sub>2</sub> heterostructure is achieved. To fabricate the optoelectronic transistor, Cr/Au source-drain electrodes (10/40 nm) are defined on the prepared Gr/MoS<sub>2</sub> heterostructure by EBL and standard lift-off process assisted with PMMA sacrifice layer. Notably, although the cover area between Gr and MoS<sub>2</sub> in fig. S3 and fig. S1 is different, the channel width and channel length of transistor between source and drain electrodes are almost same, which mainly determine the device-to-device electrical performances. Besides, graphene conductance (which is higher than MoS<sub>2</sub> conductance in this work) dominates the device current in the heterostructure, which is patterned into the same size by photolithography in each device. Furthermore, as the source-drain electrodes are selectively and precisely patterned on the Gr/MoS<sub>2</sub> heterostructure, the total cover area between Gr and MoS<sub>2</sub> beyond the channel region does not directly affect the electrical performances among different devices.





fig. S3. The optical image of each step for transistor fabrication.

#### 4. Working mechanism of the TENG coupled to transistor

As shown in fig. S4A, when Cu approaches to polytetrafluoroethylene (PTFE), some surface states in the bandgap of PTFE will be filled by electrons transferred from the Cu to the PTFE, inducing negative charges on the PTFE layers and positive charges on the Cu movable layer. Then we conduct a grounding process to release the transferred charges on Cu and PTFE friction layers. The TENG component enters an electrostatic equilibrium state, delivering no output voltage ( $V_{\text{TENG}} = 0$ ) coupling to the transistor. The relative position between PTFE and movable Cu layer is considered as the initial preset position, defined as  $D_0 = 0$ . When the two friction layers separate from the preset position (i.e., the movable Cu electrode moves to the right side, defined as  $D^+$ , fig. S4B), the electrostatic equilibrium state will be broken. The negative charges on the intrinsically electronegative PTFE are lack of restriction by the counter movable Cu electrode. Then the negative charges will be coupled to the transistor gate, equivalent to applying a negative gate voltage ( $-V_{\text{TENG}}$ ). In contrast, when the two friction layers further approach to each other from the preset position  $D_0$  (i.e., the movable Cu layer moves to the left, defined as D-, fig. S4C), more negative charges are induced on the electronegative PTFE surface and attracted to side of the movable Cu friction layer. The left positive charges on PTFE are then coupled to the transistor gate through the connected Cu electrode (PTFE/Cu friction layer). In this D- state, it is equivalent to applying a positive gate voltage  $(+V_{\text{TENG}})$ .



**fig. S4. Working mechanism of the TENG coupled to transistor.** (A) Initial state  $(D_0)$ , no output voltage  $(V_{\text{TENG}} = 0)$  coupling to the transistor. (B) Separation state (D+), equivalent to applying a negative gate voltage  $(-V_{\text{TENG}})$  to the transistor. (C) Contact state (D-), equivalent to applying a positive gate voltage  $(-V_{\text{TENG}})$  to the transistor.

#### 5. Optoelectronic characteristics of the Gr/MoS2 transistor

The optoelectronic  $Gr/MoS_2$  transistor exhibits excellent electrical performances. Schematic illustration of the  $Gr/MoS_2$  heterostructure transistor is shown in **fig. S5A**. Obvious differences between the source-drain currents ( $I_{DS}$ ) under light illumination (green LED, wavelength 525 nm) and dark state are shown in **fig. S5B**. Under the applied gate voltage ( $V_G$ ) of -40 V,  $I_D$  under light illumination is lower than that under dark state, which can be attributed to the following reason. Under negative  $V_G$ , the transport behavior of graphene is mainly determined by the holes. Light illumination induces the photogenerated electrons in  $MoS_2$  transfer to the holes-doped graphene so as to increase the graphene resistance and decrease the output current. The transfer curve of the  $Gr/MoS_2$  heterostructure transistor at dark condition is shown in **fig. S5C** (black curve), which exhibits different behaviors compared to pristine graphene or MoS<sub>2</sub> device. When the device is illuminated with a continuous green light, the current level shows a decrement trend in the region of  $V_G < V_T$  compared with  $I_D$  in dark state. Stronger light intensity leads to weaker  $I_D$ . Here,  $V_T$  is the MoS<sub>2</sub> conduction threshold, defined by the intersection between *x*-axis and the reverse extension of MoS<sub>2</sub> transfer curve (in dark state). In contrast,  $I_D$  has no significant change in the region of  $V_G > V_T$ , regardless of the light intensity. This is because the underlying MoS<sub>2</sub> exhibits prominent conductivity beyond  $V_T$ , which leads to an electrostatic screen effect on the photogenerated electrons transfer/exchange behavior in the Gr/MoS<sub>2</sub> heterostructure. The transfer curve of graphene in the dark is shown in **fig. S5D**. The Dirac voltage of graphene occurs near zero.



fig. S5. The basic optoelectronic characteristics of the Gr/MoS<sub>2</sub> heterostructure transistor. (A) Schematic illustration of the Gr/MoS<sub>2</sub> heterostructure transistor illuminated with a green light-emitting diode (LED, wavelength 525 nm). (B) Output characteristics of the Gr/MoS<sub>2</sub> transistor in dark state (black curve) and under continuous illumination by the green LED (green curve), the photoexcitation intensity ( $P_{\text{LED}}$ ) is 0.73 mW·cm<sup>-2</sup>. (C) Transfer characteristics of Gr/MoS<sub>2</sub> transistor in the dark and under light illumination at  $P_{\text{LED}} = 27 \text{ mW} \cdot \text{cm}^{-2}$  and  $P_{\text{LED}} = 0.73 \text{ mW} \cdot \text{cm}^{-2}$ . The yellow curve corresponding to the right *y*-axis is the transfer curve of pristine MoS<sub>2</sub> transistor under dark state. We plot the  $I_D$  of MoS<sub>2</sub> transistor in linear scale versus  $V_G$  to extract the MoS<sub>2</sub> conduction threshold ( $V_T$ ). (D) Transfer curve of pure graphene channel in the dark.

#### 6. Photocurrent and photoresponsivity of Gr/MoS<sub>2</sub> heterostructure transistor

The photocurrent  $(I_P)$  of Gr/MoS<sub>2</sub> transistor is defined as the current difference between the  $I_{\rm D}$  in dark state and  $I_{\rm D}$  under light illumination. Higher light intensity induces more photogenerated electrons transfer from MoS<sub>2</sub> to the holes-doped graphene (under negative  $V_{\rm G}$ ), which increases the resistance of graphene and leads to the current decrement (reflected as a negative  $I_P$ ) under light illumination. Consequently,  $I_P$  decreases from -2.4 to -46  $\mu$ A with  $P_{\text{LED}}$  increased from 0.9  $\mu$ W·cm<sup>-2</sup> to 13.2 mW·cm<sup>-2</sup> at an applied  $V_{\text{G}}$  of -40 V (fig. S7A). The  $I_P$  level shows an enlarged variation range with the decreased  $V_G$ , which can be attributed to that more heavily holes-doped graphene under more negative  $V_{\rm G}$  (e.g.,  $V_{\rm G}$  = -40 V) delivers more space/opportunities to be interfered by the photogenerated electrons from MoS<sub>2</sub>. The photoresponsivity ( $\gamma$ ) of the transistor, indicating the photoresponse under different light intensities, can be evaluated from the equation of  $\gamma = I_P/P_{LED}$ . Here, the  $\gamma$  of the Gr/MoS<sub>2</sub> heterostructure transistor approximates to the maximum value of  $4.4 \times 10^7$  A/W at  $V_{\rm G} = -40$  V, drain voltage  $V_{\rm D} = 1$  V, and  $P_{\rm LED} = -10$  mW·cm<sup>-2</sup> (fig. S7B). The  $\gamma$  is determined by both  $V_{\rm G}$  and  $P_{\rm LED}$  according to the results in fig. S7B. Under the same  $P_{\rm LED}$ ,  $\gamma$  increases from  $1.8 \times 10^7$  to  $4.4 \times 10^7$  A/W with V<sub>G</sub> decreased from -20 to -40 V. This is attributed to that more heavily holes-doped graphene at smaller  $V_{\rm G}$  is more susceptive to the photogenerated electrons transferred from  $MoS_2$ , resulting in the relatively larger  $I_P$ . On the other hand,  $\gamma$  exhibits a decrement trend with increased  $P_{\text{LED}}$  at the same  $V_{\text{G}}$ . This phenomenon can be explained by the relatively smaller magnitude of the photocurrent (few tens) under light illumination compared to the much larger variation range of  $P_{\text{LED}}$  (10<sup>4</sup> orders of magnitude).



fig. S6. Photocurrent and photoresponsivity of Gr/MoS<sub>2</sub> heterostructure transistor. (A) The photocurrent and (B) photoresponsivity  $\gamma$  of the Gr/MoS<sub>2</sub> heterostructure transistor vs.  $P_{\text{LED}}$  at different  $V_{\text{GS}}$ .

#### 7. MoS<sub>2</sub> thickness influence on the photocurrent and photoresponsivity

We prepared a control sample of  $Gr/MoS_2$  heterostructure transistor with thicker  $MoS_2$  layer (> 50 nm), both the electric performances and photoresponses are observed to be related with heterostructure thickness (**fig. S6**). The photoresponse is obviously smaller than that in the 32 nm thick  $Gr/MoS_2$  heterostructure. The properties of persistent photoconductivity, which are mainly determined by the physical separation of the electrons and holes by the interfacial (or potential) barrier within the heterostructures, may also be significantly

influenced due to the exponentially decreased direct tunnelling current in the heterojunction with larger thickness (55). When  $MoS_2$  layer number in the heterostructure is smaller (e.g., reduced to two layer), the electric field-induced interface barrier will be suppressed, which also leads to the weakened photoresponsivity and persistent photoconductivity (39). Accordingly, the optimization of  $MoS_2$  thickness in the heterostructure is critical to the device photosensitivity and electrical performances, which can potentially influence the eventual device-level or system-level applications of  $Gr/MoS_2$  heterostructure.



fig. S7. The optoelectronic characterization of Gr/MoS<sub>2</sub> transistors with different MoS<sub>2</sub> thicknesses. (A) Thin. (B) Thick.

#### 8. The output characteristics of mechano-optoelectronic Gr/MoS2 transistor

To characterize the mechano-optoelectronic transistor, the output performances are measured under the synergistic effects of TENG displacement and light illumination states as shown in **fig. S8** (dark state,  $P_{\text{LED}} = 27 \ \mu\text{W} \cdot \text{cm}^{-2}$ , and  $P_{\text{LED}} = \sim 0.73 \ \text{mW} \cdot \text{cm}^{-2}$  states). In the dark state (**fig. S8B**),  $I_{\text{D}}$  shows an obvious increment (from 328 to 386  $\mu$ A) with increased TENG displacement (*D*, from -1.5 to 1.5 mm stepped by 0.25 mm) at  $V_{\text{D}} = 1 \text{ V}$ . Under light illumination at  $P_{\text{LED}} = 27 \ \mu\text{W} \cdot \text{cm}^{-2}$  (**fig. S8C**),  $I_{\text{D}}$  increases from 327 to 362  $\mu$ A with the same variation of *D*. In contrast, under light illumination at  $P_{\text{LED}} = \sim 0.73 \ \text{mW} \cdot \text{cm}^{-2}$  (**fig. S8D**),  $I_{\text{D}}$  shows no obvious variation under the triboelectric potential modulation with *D* varies from -1.5 to 1.5 mm (stepped by 0.25 mm). This may be attributed to that the more photogenerated electrons are induced in MoS<sub>2</sub> under stronger light illumination, which screen partial of the triboelectric potential and weaken its gating efficiency on graphene channel.



fig. S8. The output characteristics of the mechano-optoelectronic transistor based on graphene/MoS<sub>2</sub> heterostructure. (A) Schematic diagram of the mechano-optoelectronic transistor illuminated with a green LED. Output curves in dark state (B), under light illumination at  $P_{\text{LED}} = 27 \,\mu\text{W}\cdot\text{cm}^{-2}$  (C), and at  $P_{\text{LED}} = 0.73 \,\text{mW}\cdot\text{cm}^{-2}$  (D), with  $V_{\text{D}}$  from -1 to 1 V and D from -1.5 to +1.5 mm stepped by 0.25 mm.

### 9. Photocurrent and photoresponsivity of mechano-optoelectronic Gr/MoS<sub>2</sub> transistor

To further desmonstrate the synergistic effect of TENG displacement and light illumination, the influence of mechanical displacement D on the photocurrent and photosensitivity is investigated in **fig. S9**. Under the light illumination at  $P_{\text{LED}} = 11.5 \text{ mW} \cdot \text{cm}^{-2}$ , the photocurrent increases from -1.4 to -53.4  $\mu$ A with D increased from 0.5 to 1.5 mm stepped by 0.25 mm. The calculated photosensitivity also shows an increment tendecy with the increased D, varying from  $2.4 \times 10^4$  to  $9.3 \times 10^5$  A/W. Larger displacement ( $D^+$ ), equivalent to applying more negative  $V_G$ , induces higher photocurrent and photoresponsivity due to the electrostatic field dependent Fermi level and electronic states in the heterostructure. These results indicate the mechanical displacement (intrinsically tuned by the induced triboelectric potential). The synergistic modualtion on the optoelectronic properties of the transistor by mechanical displacement and light illumination is the foundation of mix-modal and crossmodal plasticization in synaptic devices.



**fig. S9.** The photocurrent (bottom) and photoresponsivity  $\gamma$  (top) vs.  $P_{\text{LED}}$ , D varies from 0.5 to 1.5 mm stepped by 0.25 mm.

#### 10. Decay time evaluation of mechano-optoelectronic Gr/MoS2 transistor

To distinguish from the retention time, the decay time ( $\tau$ ) for the post synaptic current (PSC) is defined as the time of PSC decreasing from the peak current to the steady current level, which can be fitted by the typical exponential decay model with the following equation:

$$I(t) = I_{\infty} + (I_{\text{peak}} - I_{\infty}) \cdot \exp\left[\left(\frac{-(t-t_0)}{\tau}\right)^{\beta}\right],$$

where  $\tau$  is the decay time,  $t_0$  is the time at which the presynaptic spike finishes,  $\beta$  is the correction factor (here  $\beta = 0.5$ , which can be well fitted),  $I_{\text{peak}}$  is the amplitude of the EPSC, and  $I_{\infty}$  is the steady value of the decay current.

To evaluate the decay time, we measured a series of post synaptic currents under different displacements and different illumination powers, respectively (**fig. S10**).



fig. S10. The - $\Delta$ PSCs under different displacements and different illumination powers. (A)  $P_{\text{LED}}=0.73 \text{ mW} \cdot \text{cm}^{-2}$ . (B)  $P_{\text{LED}}=1.8 \text{ mW} \cdot \text{cm}^{-2}$ . (C)  $P_{\text{LED}}=2.8 \text{ mW} \cdot \text{cm}^{-2}$ . (D)  $P_{\text{LED}}=3.5 \text{ mW} \cdot \text{cm}^{-2}$ . (E)  $P_{\text{LED}}=8.2 \text{ mW} \cdot \text{cm}^{-2}$ . (F)  $P_{\text{LED}}=13.5 \text{ mW} \cdot \text{cm}^{-2}$ .

11. 3D plotting of decay time versus both displacement and light illumination power The decay time  $\tau$  for the post synaptic current is plotted as a function of both displacement and illumination power, as shown in **fig. S11**. When the illumination power is 13.5 mW·cm<sup>-2</sup>, the decay time increases from 3.33 to 4.47 s with displacement increased from 0.75 to 1.5 mm. When the displacement is fixed at 1 mm, the decay time increases from 0.96 to 4.31 s with the illumination power increased from 0.73 mW·cm<sup>-2</sup> to 13.5 mW·cm<sup>-2</sup>.



fig. S11. 3D plotting of decay time vs. displacement and light illumination power.

#### 12. Retention time of the mechano-photonic artificial synapse

To evaluate the retention time, the postsynaptic currents at different voltages under  $P_{\text{LED}} = 3.5 \text{ mW} \cdot \text{cm}^{-2}$  are measured in **fig. S12.** The intrinsic retention time of the mechano-photonic artificial synapse is evaluated to be capable of retaining for over one hour without significant changes, which also shows potential to be retained for longer time estimated from the curves (consistent with the near-perfect charge retention in previous report (39)).



fig. S12. Retention time of the mechano-photonic artificial synapse.

### 13. Band diagram of mechano-optoelectronic Gr/MoS<sub>2</sub> transistor after switching off light

Under  $D^+$  state (negative triboelectric potential), the equivalent negative  $V_G$  applied to the transistor shifts the Fermi level of graphene downwards. In this state, holes dominantly contribute to the transport properties of graphene. The light illumination induces the electron-hole pairs to separate in MoS<sub>2</sub> and thereby pulls its energy band downward. The photogenerated electrons in MoS<sub>2</sub> are driven to graphene due to the equivalent negative  $V_G$  applied to the device. When the light is switched off, a small portion of the transferred electrons reversely diffuse to MoS<sub>2</sub> and lead to a slight recovery of  $I_D$  as shown in **Fig. 3b**. The subsequently persistent  $I_D$  arises from the potential barrier against the reverse diffusion of photogenerated electrons due to the graphene-on-MoS<sub>2</sub> heterostructure.



fig. S13. Schematic illustration of the band diagram when the light is turned off.

#### 14. Postsynaptic currents (PSCs) at applied displacement smaller than 0.5 mm

When the applied  $D^+$  is smaller than 0.5 mm and gradually decreases, the equivalent  $V_G$  tends to increase to be positive and approach  $V_T$  (the MoS<sub>2</sub> conduction threshold). The MoS<sub>2</sub> starts to exhibit significant transport properties, which suppress the injection of photogenerated electrons to graphene. As a consequence, the postsynaptic currents (PSCs) exhibit slight variation (i.e., - $\Delta$ PSC). At applied different D (0.5, 0.25 and 0 mm), the peak value of - $\Delta$ PSC is decreased from 7 to 1  $\mu$ A, with almost no obvious PSC change at D = 0.



**fig. S14.** The PSC response of the mechano-photonic artificial synapse at fixed D of 0.5, 0.25, and 0 mm. The applied  $P_{\text{LED}}$  is 3.5 mW·cm<sup>-2</sup> with pulse width at 0.5 s.

#### 15. The erasing process of persistent PSC by TENG contact pulse (D-)

The persistent PSC of mechano-photonic artificial synapse can be readily erased by applying TENG contact pulse (*D*-), which is equivalent to applying more positive  $V_{\rm G}$ . As shown in **fig. S15**, different PSCs achieved under the synergetic modulation of light pulse ( $P_{\rm LED} = 3.5 \text{ mW} \cdot \text{cm}^{-2}$ , pulse width 0.1 s) and different *D*+ statuses (0.5, 1, and 1.5 mm) are successfully erased by applying *D*- pulse. This is because the coupled positive triboelectric potential under *D*- pulse instantaneously raises the Fermi energy over  $V_{\rm T}$  and redistributes the charge carriers in Gr/MoS<sub>2</sub> heterostructure.



fig. S15. The erasing process of persistent PSC by TENG contact pulse (D-).

#### 16. - $\Delta$ PSC of the synaptic device under forty consecutive light pulses at D = 1 mm

When forty consecutive light pulses ( $P_{\text{LED}} = 3.5 \text{ mW} \cdot \text{cm}^{-2}$ , pulse width = 50 ms) are applied to the synapse device at D = 1 mm, the amplitude value of - $\Delta$ PSC gradually increases to 20  $\mu$ A and tends to be stabilized at ~ 33  $\mu$ A. The gain value of - $\Delta$ PSC, which is defined as  $A_n/A_1$  (A is the amplitude of the - $\Delta$ PSC peak value), can reach132% after the stimulation of consecutive light pulses for forty times (**fig. S16**).



fig. S16. - $\Delta$ PSC under forty consecutive light pulses at D = 1 mm. (A) - $\Delta$ PSCs under forty consecutive light pulses ( $P_{\text{LED}} = 3.5 \text{ mW} \cdot \text{cm}^{-2}$ , pulse width = 50 ms, D = 1 mm). Inset: the enlarged first - $\Delta$ PSC peak  $A_1$  (left) and last current peak  $A_n$  (right). (B) The current gain (defined as the ratio of  $A_n/A_1$ ) vs. light pulse number.

### 17. Depression/potentiation (D/P) curve for artificial neural network (ANN) simulation

The D/P curve (**fig. S17**) used for ANN simulation is characterized with the variation of  $-\Delta$ PSC, which is achieved by applying forty consecutive light pulses at a displacement of 1.5 mm to implement the depression process (negative increment, i.e., the depression region) and applying forty additional TENG displacement pulses (D = 0.1 mm) to implement the potentiation process (positive increment, i.e., the potentiation region). In this work, utilizing photonic depression and mechanical potentiation to achieve the D/P curve for ANN simulation is mainly attributed to the following two reasons.

Firstly, under light illumination, the drain current ( $I_D$ ) of Gr/MoS<sub>2</sub> transistor shows a decrement tendency with the increased light intensity in the region of  $V_G < V_T$ . Due to the exhibited negative photoconductivity, the optical synaptic behavior of the device can only be depressed (i.e., the current is decreased under light illumination) with no potentiation behaviors under D = 1.5 mm.

Secondly, based on the synergistic mechano-photonic dual-mode modulation on synaptic plasticity, we can use additional displacement pulses (D = 0.1 mm, equivalent to negative  $V_{\rm G}$ ) consecutively applied to the artificial synapse to modulate the carrier density in graphene channel and achieve the potentiation behaviors.



fig. S17. Depression/potentiation (D/P) curve used for ANN simulation.

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